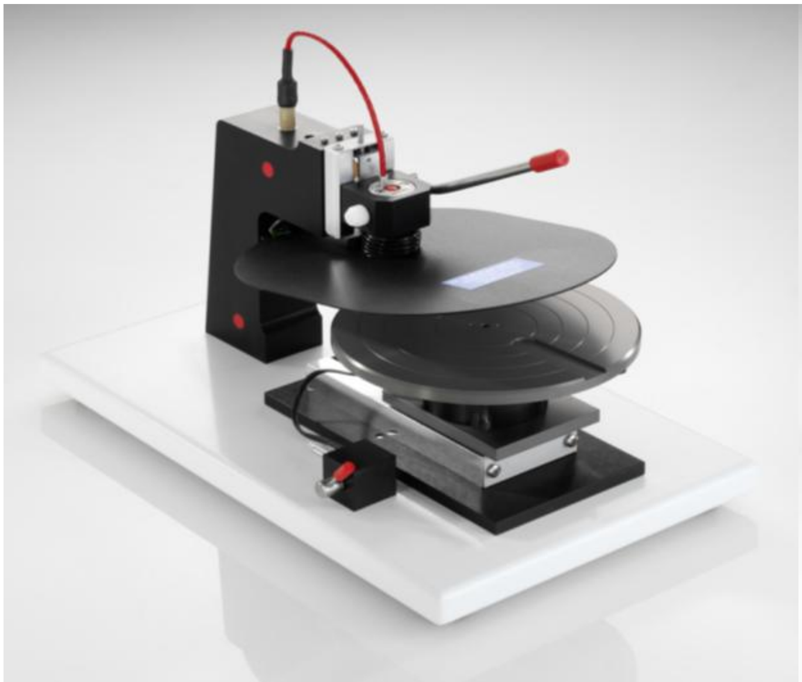
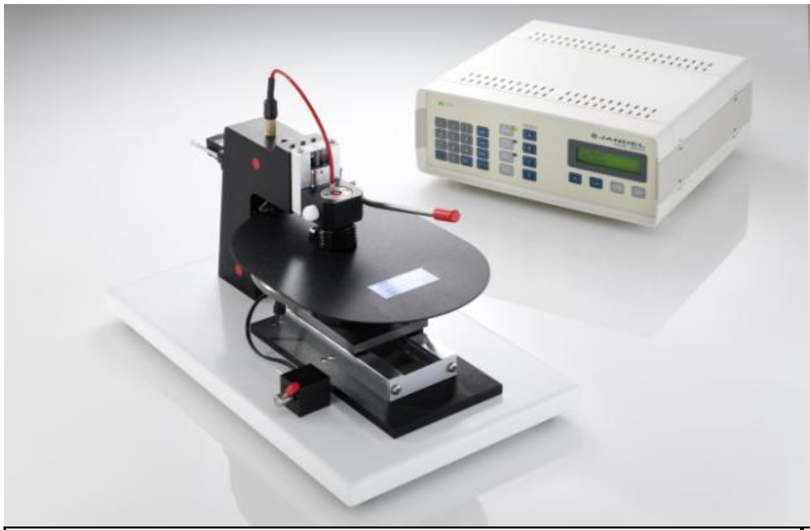
JANDEL

Multiposition Wafer Probe with RM3-AR Test Unit



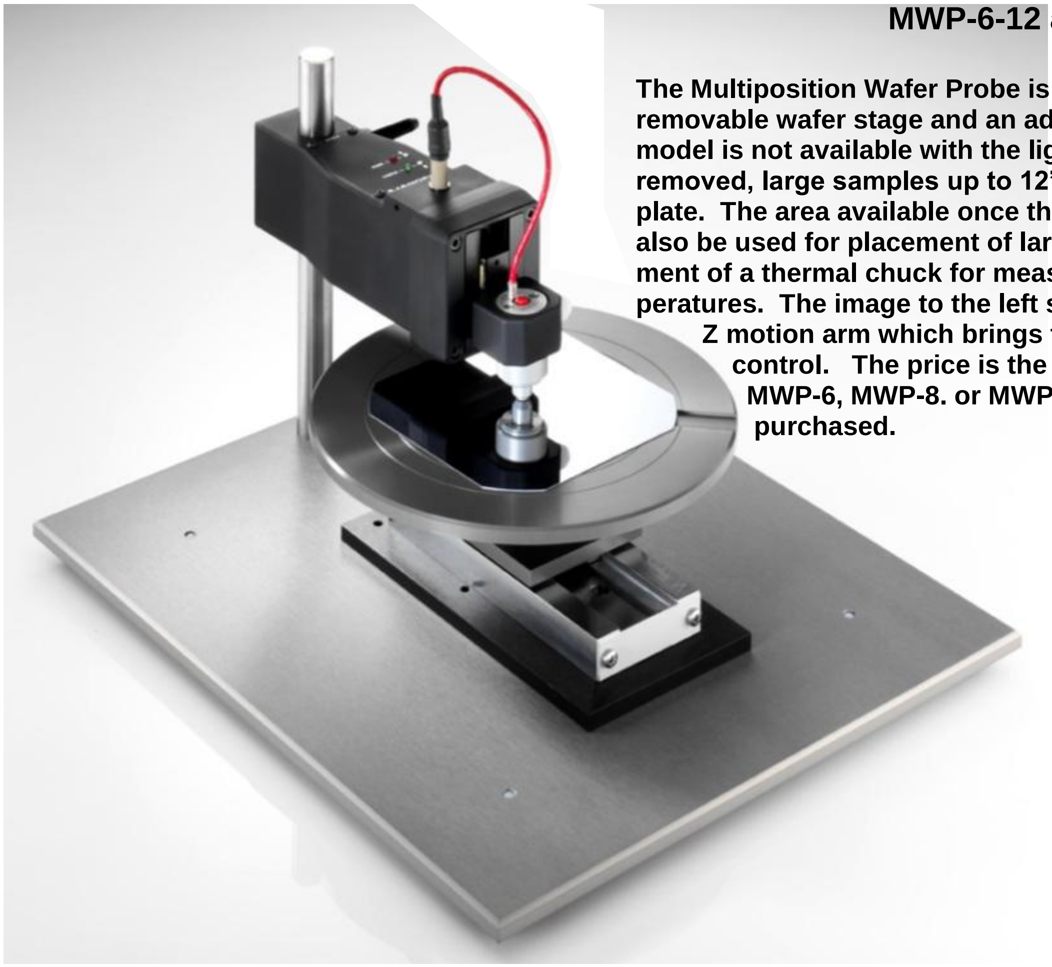


MWP-6 and RM3-AR
6” (150mm) model

MWP-8 and RM3-AR
8” (200mm) model

MWP-6-12 and MWP-8-12

The Multiposition Wafer Probe is available in a version which has a removable wafer stage and an adjustable height probe arm. This model is not available with the light shield. When the wafer stage is removed, large samples up to 12” x 12” can be placed upon the base plate. The area available once the wafer stage has been removed can also be used for placement of large samples such as ingots, or placement of a thermal chuck for measuring resistivity at elevated temperatures. The image to the left shows the optional AFPP Automatic Z motion arm which brings the probe into contact under motor control. The price is the same regardless of whether the MWP-6, MWP-8. or MWP-6-12 or MWP-8-12 (as shown) is purchased.



MWP-8-12 with Wafer Stage Removed, Probing onto a 300mm (12”) Wafer

Shown with Optional AFPP Automatic Z Motion Arm